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BIB DATA SHEET

CONFIRMATION NO. 2213

SERIAL NUM			CLASS		GRO	GROUP ART UNIT		ATTORNEY DOCKET		
10/598,933		DATE 09/14/2006			505		2886		PA214WP002	
		RULE								
APPLICANTS Fumi Nabeshima, Hiratsuka-shi, JAPAN; Kazuya Togashi, Hiratsuka-shi, JAPAN; Hiroshi Jiken, Hiratsuka-shi, JAPAN; Yoshinori Suenaga, Hiratsuka-shi, JAPAN; ** CONTINUING DATA **************************** This application is a CON of PCT/JP05/07120 04/13/2005 ** FOREIGN APPLICATIONS ************************************										
Foreign Priority claims 35 USC 119(a-d) cond Verified and Acknowledged	ditions met	Yes No Yes No NNOOSE/ Signature	Met af Allowa	ter ince	STATE OR COUNTRY JAPAN	_	EETS WINGS	TOT. CLAII		INDEPENDENT CLAIMS 2
ADDRESS JOSEPH P. FARRAR 2-4-6 TSUKUDA SUITE 709 CHUO-KU, TOKYO, 104-0051 JAPAN										
TITLE										
Semiconductor wafer inspection device and method										
	EEEC: Authority has been given in Denoy					☐ All Fees ☐ 1.16 Fees (Filing)				
	FEES: Authority has been given in Paper No to charge/credit DEPOSIT ACCOUNT No for following:						☐ 1.17 Fees (Processing Ext. of time)			
1130							1.18 Fees (Issue)			
							Other			
☐ Credit										